

Ultra-Sensitive 2D Photodetectors Based on Large-Scale Molybdenum Disulfide Crystals

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Abstract

We report the demonstration of ultra-sensitive two-dimensional photodetectors based on large-scale (1x2 cm²) MoS₂ crystals synthesized by magnetron sputtering. Excellent film uniformity and precise control of the MoS₂ thickness down to a monolayer (~0.75nm) were achieved. Using gold-free CMOS compatible processes, the photodetectors were realized with a wide spectral response from the visible to the near-infrared band. In particular, photodetectors with five MoS₂ monolayers exhibited high photoresponsivity of 1.8A/W, external quantum efficiencies exceeding 260%, and photo-detectivities of >10⁸ Jones, surpassing the performance of mechanically exfoliated based photodetectors. Such synthesis approach shows promising scalability to wafer level in meeting the industrial requirements for optical communication applications.

1. Introduction

Transition metal dichalcogenides materials such as molybdenum disulfide (MoS₂) have attracted great attention arising from the ability to isolate individual, atomically thin layers with unique electronic and optical properties from its bulk form. Previous approaches for obtaining thin MoS₂ layers include micromechanical exfoliation by scotch-tape [1] and chemical vapor deposition [2]. Among other challenges, these techniques are reported to have poor uniformity and repeatability in producing the desired film thickness and geometry.

This work addresses the above issues by using a physical vapor deposition (PVD) technique such as magnetron sputtering to synthesize highly uniform MoS₂ films with a precise control of thickness down to a monolayer over a large area (1x2 cm²) substrate. Using gold-free CMOS compatible processes, MoS₂ photodetectors with ohmic contacts were demonstrated and method to enable further performance improvement was explored. Impressive optical response was achieved over a wide spectral range from the visible to the near-infrared band, which were shown to outperform the primitive 2D photodetectors fabricated by mechanical exfoliation.

2. Synthesis of Large Area MoS₂ Crystals

Our PVD synthesis involves the growth of atomically thin MoS₂ films by DC magnetron sputtering of Molybdenum target in a vaporized sulfur ambient, using a substrate temperature of 700°C, Sulfur partial pressure of 4.0x10⁻⁷ millibars, Argon pressure of 6.0x10⁻⁴ millibars and a low sputtering power of 6W [3]. Using this low sputtering power, the growth rate can be controlled to a high precision. The sputtered molybdenum atoms react with the vaporized sulfur atoms before landing onto the heated HfO₂ dielectric / silicon substrate to form MoS₂ layers (Fig. 1). Excellent thickness uniformity is demonstrated for 2ML MoS₂ from the matching Raman peaks on three independent locations along the film as shown in Fig. 2. Fig. 3 shows that similar to exfoliated MoS₂ films, the difference between the Raman peaks (Δ) corresponding to the in-plane E_{2g}^1 phonon mode and the out-of-plane A_{1g} phonon mode increases with more layers. A precise control of the MoS₂ thickness is achieved, showing an average monolayer thickness of 0.75nm, and a low deviation of 5% (Fig. 4).

3. Device Fabrication

Fig. 5 shows the gold-free CMOS compatible fabrication process flow of the PVD-synthesized MoS₂ photodetector, in which ohmic contact is formed using titanium (Ti) metal electrodes fabricated via an evaporation and lift-off process. The final photodetector device structure is as shown in Fig. 6, whereby the performance is evaluated across a wide spectral range from the visible to the near-infrared band for varying film thicknesses and channel biases.

4. Results and Discussions

Fig. 7 and 8 show the improvements in photocurrent and thus the photoresponsivity with increasing number of MoS₂ layers. While the 2ML photodetector exhibits a photocurrent of ~10 μ A and a photo-responsivity of ~0.4A/W in the visible region, a significant increase by four times is achieved for the 5ML photodetector. Interestingly, although the exfoliated MoS₂ films generally show a blue shift of the optical bandgap with reducing layers, Fig. 8 shows that the PVD-synthesized MoS₂ photodetectors exhibit an extended optical absorption over a wide spectral range up to near-infrared (1200 nm) for all three investigated thicknesses (2ML, 3ML and 5ML), which is close to the bandgap of bulk MoS₂ [4]. One underlying mechanism could be attributed to the internal film strain commonly induced by the PVD synthesis [5],[6], which leads to a shrinkage in MoS₂ bandgap energy.

Fig. 9 shows the deconvolution of the measured XPS spectrum, in which the Mo and S peak binding energy positions and its linewidths are extracted. With increasing MoS₂ thickness, a clear shift in the S 2s peak binding energy position and linewidth is observed, which supports the presence of strain effect in the MoS₂ films (Fig. 10). Strain relaxation eventually occurs near the front surface in thicker MoS₂ film, as evident from the high RMS surface roughness (Fig. 11).

Even for an atomically thin 2ML photodetector, a high photodetectivity exceeding 10⁹ Jones is observed in Fig. 12, which outperforms the 3ML and 5ML photodetectors. This is primarily attributed to a significantly lower dark current in thinner MoS₂ films (Fig. 13). Fig. 14 shows the performance benchmarking of large scale MoS₂ photodetector demonstrated in this work over the exfoliated MoS₂, CVD MoS₂, and graphene based photodetectors [7-12]. Clearly, photodetectors enabled by large area MoS₂ synthesis show promising performance in addition to delivering better scalability.

Fig. 15 shows that increasing the channel bias not only enhances the charge collection efficiency, but also has the potential for causing carrier multiplication through impact ionization process due to a high electric field strength across the channel. This is confirmed from the external quantum efficiency (EQE) curves exceeding 100%. Furthermore, thicker MoS₂ layers are shown to benefit from increased photo-responsivity and EQE across all investigated channel bias (Fig. 16). Stable switching characteristics were also demonstrated on these MoS₂ photodetectors (Fig. 17), while Fig. 18 highlights further improvement in the rise and fall time with increasing channel bias.

5. Conclusion

Ultra-sensitive 2D photodetectors based on large-scale MoS₂ crystals were successfully demonstrated using gold-free CMOS compatible processes. Synthesized by magnetron sputtering, a precise control of the MoS₂ film thickness and uniformity was achieved over a large area substrate, with potential of scaling up to wafer level. The MoS₂ photodetectors were evaluated with a wide spectral response from the visible to the near-infrared band, showing great potential for optical communication applications.

References

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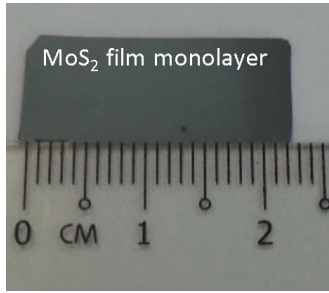


Fig. 1. Optical microscopy image of the PVD-synthesized MoS₂ films deposited on the HfO₂/ Silicon substrate.

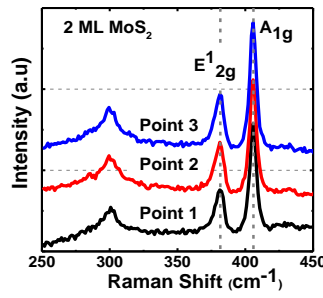


Fig. 2. Excellent film uniformity for PVD-synthesized MoS₂ films as thin as two monolayers.

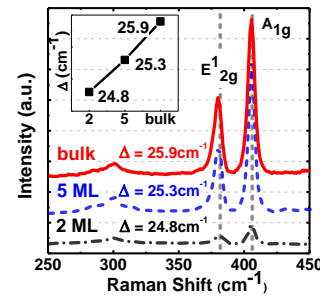


Fig. 3. Larger Raman E_{12g} spectra peak shifts is observed with increasing number of MoS₂ layers.

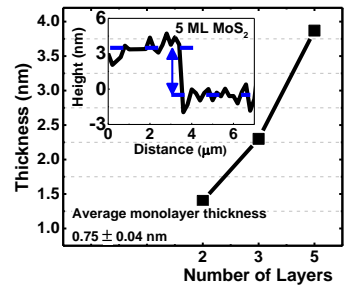


Fig. 4. Precise control of number of PVD-synthesized MoS₂ layers with low thickness deviation (~5%).

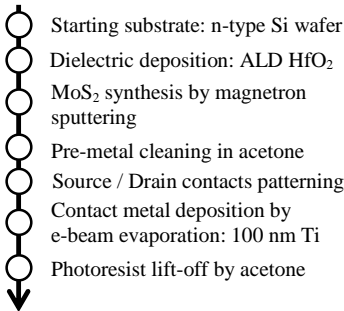


Fig. 5. Fabrication process flow of the PVD-synthesized MoS₂ photodetectors.

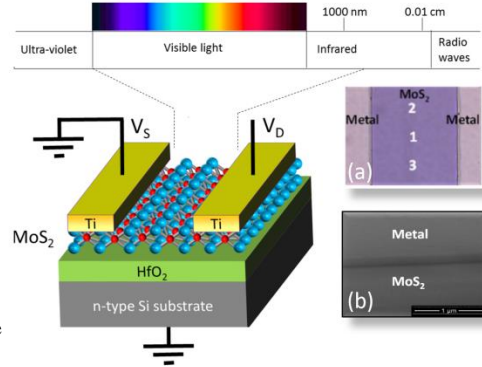


Fig. 6. Schematic of the MoS₂ photodetectors, evaluated across a wide spectral range from 400 nm to 1250 nm. Inset (a) and (b) show the optical and SEM micrograph image, respectively.

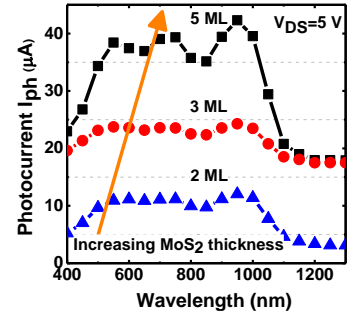


Fig. 7. Increasing photocurrent (I_{ph}) with increasing number of MoS₂ layers due to enhanced photo-absorption.

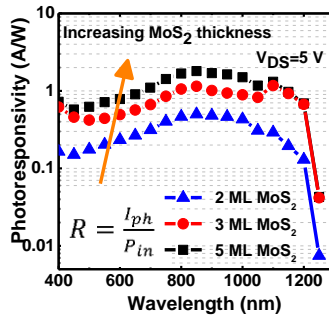


Fig. 8. Increasing photoresponsivity (R) is achieved with increasing number of MoS₂ layers.

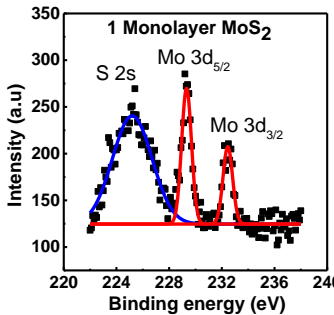


Fig. 9. A deconvolution of the XPS spectrum for the single monolayer MoS₂ film.

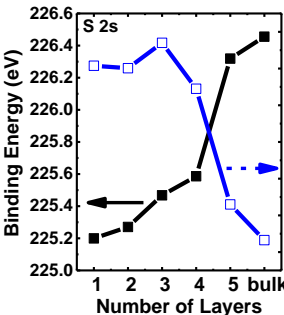


Fig. 10. S 2s peak binding energy position increases, and FWHM decreases as MoS₂ layer increases.

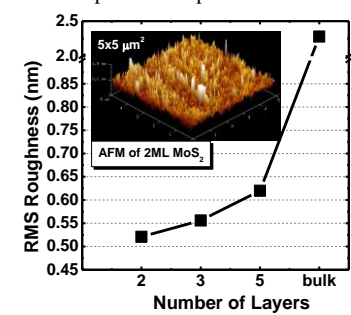


Fig. 11. RMS surface roughness increases with MoS₂ layers. Inset: 3D AFM image for the 2 ML MoS₂ film.

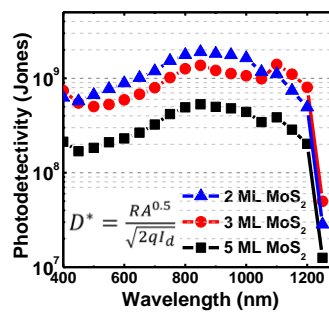


Fig. 12. Increased photodetectivity (D^*) with thinner MoS₂ layers due to lower dark current level.

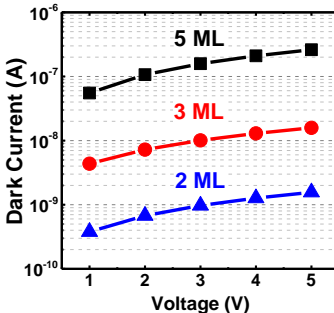


Fig. 13. Lower dark current (I_d) with thinner MoS₂ layers, giving rise to higher photodetectivity.

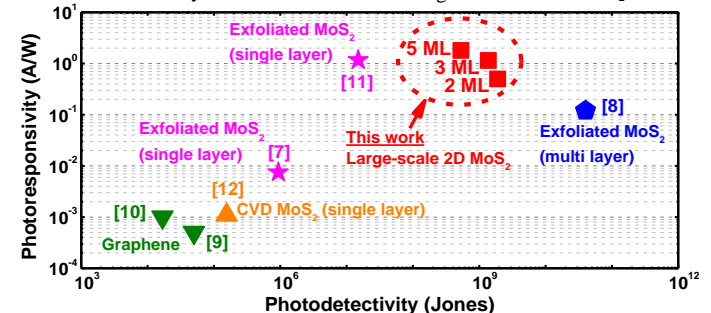


Fig. 14. The PVD-synthesized MoS₂ photodetectors demonstrated in this work outperform the previously reported MoS₂ photodetectors based on mechanical exfoliation, and CVD techniques, as well as Graphene-based photodetectors.

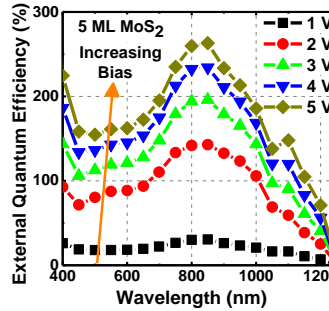


Fig. 15. Increasing external quantum efficiency with increasing applied bias across a wide spectra region.

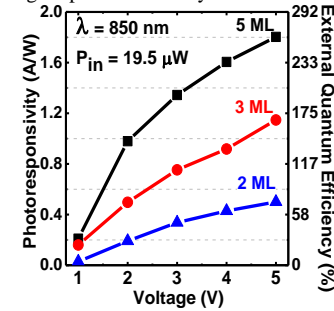


Fig. 16. Increasing bias leads to higher R and EQE , which enhances further with thicker MoS₂ layers.

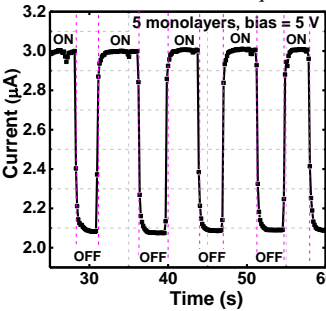


Fig. 17. A stable switching characteristics of the PVD-synthesized MoS₂ photodetector.

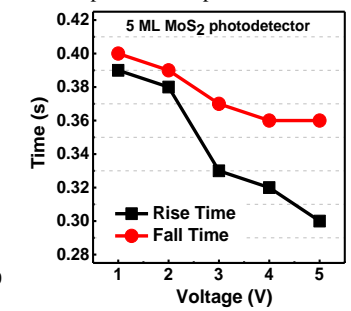


Fig. 18. Increasing channel bias reduces the rise and fall time of the MoS₂ photodetector.